

Title (en)
MICROMIRROR SYSTEMS

Title (de)
MIKROSPIEGELSYSTEME

Title (fr)
SYSTEMES DE MICROMIROIRS

Publication
EP 1588202 A4 20071010 (EN)

Application
EP 03774800 A 20031010

Priority

- US 0332348 W 20031010
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- US 26976302 A 20021011
- US 26947802 A 20021011

Abstract (en)
[origin: WO2004034103A2] Micromirror devices, especially for use in digital projection are disclosed. Other applications are contemplated as well. The devices employ a superstructure that includes a mirror supported over a hinge set above a substructure. Various improvements to the superstructure over known micromirror devices are provided. The features described are applicable to improve manufacturability, enable further miniaturization of the elements and/or to increase relative light return. Devices can be produced utilizing the various optional features described herein, possibly offering cost savings, lower power consumption, and higher resolution.

IPC 8 full level
G02B 7/182 (2006.01); **G02B 17/06** (2006.01); **G02B 26/00** (2006.01); **G02B 26/08** (2006.01); **G02B 26/12** (2006.01); **G02B 27/18** (2006.01)

IPC 8 main group level
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CPC (source: EP)
G02B 26/0841 (2013.01)

Citation (search report)

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- [A] US 2002071171 A1 20020613 - GREYWALL DENNIS S [US]
- See references of WO 2004034103A2

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DOCDB simple family (publication)
WO 2004034103 A2 20040422; WO 2004034103 A3 20050811; AU 2003282611 A1 20040504; CA 2502298 A1 20040422; EP 1588202 A2 20051026; EP 1588202 A4 20071010; JP 2006502449 A 20060119

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